

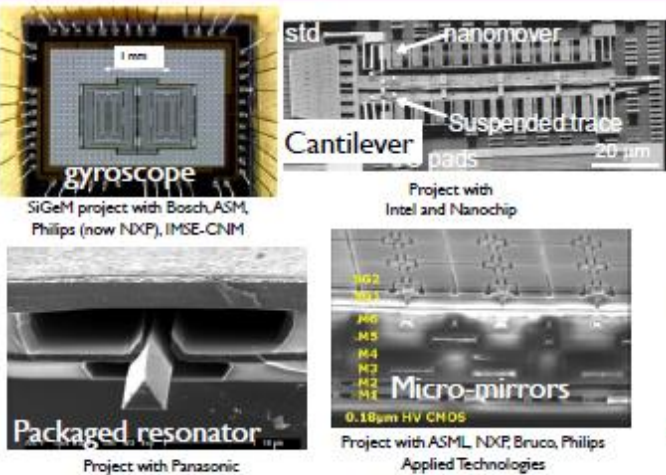
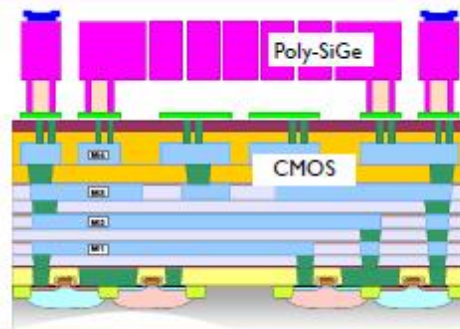
IMEC: HOME OF SiGe MEMS

Background

In imec's 200mm fab a dedicated **poly-SiGe above-IC MEMS** (Micro Electro-Mechanical Systems) platform has been set up to integrate MEMS and its readout and driving electronics on one chip. This monolithic approach results in more compact systems with a reduced assembly and packaging cost and a higher performance than current hybrid systems.

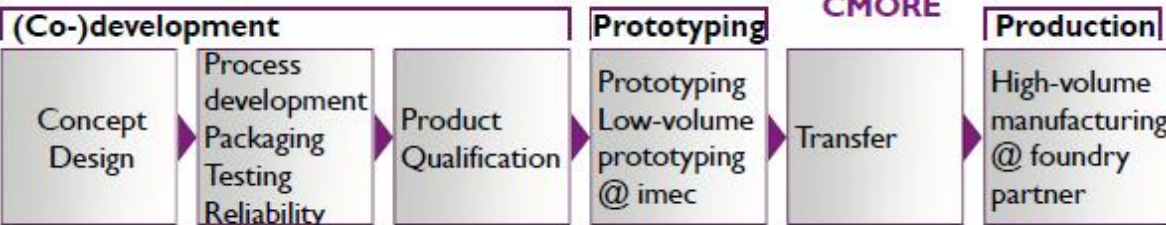
Platform

The **SiGe MEMS platform** consists of a number of standard modules: CMOS protection layer, MEMS via and poly-SiGe electrode, anchor and poly-SiGe structural layer and an optional thin-film poly-SiGe packaging module. Extra modules, such as a piezoresistive layer (see exhibit #1) can be added depending on the functionality that is needed.



Demonstrators

With this platform and together with our partners, several **successful demonstrators** have been built already. Examples are an integrated gyroscope for automotive applications (exhibit #2), a reliable 11 megapixel micro-mirror array for high-end industrial applications (exhibit #3), a cantilever array for probe-based data storage, SiGe thin film packaged SOI resonators with quality factors >200 000, ...



CMORE service

This SiGe platform is one of the technologies that imec offers to industrial customers through our **CMORE service**. Within CMORE innovative concepts are turned into products. Academic customers can make use of the SiGe **MPW service** within **Europractice** (exhibit #4)

